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Title: Ellipsometric and reflectometric characterization of thin films exhibiting thickness non-uniformity and boundary roughness

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Highlights

- Thin films with rough overlayers and thicknes non-uniformity are studied
- New formulae for optical quantities of films with both defects are derived
- Combination of the scalar diffraction theory and Rayleigh-Rice theory is used
- Method of the optical characterization of films with such the defects is developed
- This method is applied to epitaxial ZnSe thin films